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Increasing Plasma Intensity in a Hollow Cathode Light Source with a Magnetic Field ANTHONY WILLEY, Brigham Young University — In an effort to get higher EUV intensity, a hollow cathode plasma light source was wrapped in a solenoid to create a magnetic field in the plasma region. Confining the plasma toward the center of the source was expected to increase the intensity of the He II 304 A and He 584 A lines. An applied magnetic field of about 150 gauss increased intensity of the 584 A line, but decreased intensity at the 304 A line.

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